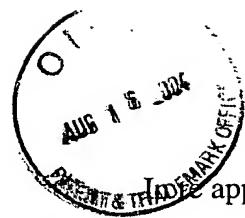




**PATENT APPLICATION**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**



application of

Docket No: Q79656

Markus MENGEL

Appln. No.: 10/765,904

Group Art Unit: Not Yet Assigned

Confirmation No.: 2613

Examiner: Not Yet Assigned

Filed: January 29, 2004

For: **METHOD AND APPARATUS FOR SPATIALLY RESOLVED POLARIMETRY**

**INFORMATION DISCLOSURE STATEMENT**  
**UNDER 37 C.F.R. §§ 1.97 and 1.98**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In accordance with the duty of disclosure under 37 C.F.R. § 1.56, Applicant hereby notifies the U.S. Patent and Trademark Office of the documents which are listed on the attached PTO/SB/08 A & B (modified) form and/or listed herein and which the Examiner may deem material to patentability of the claims of the above-identified application.

One copy of each of the listed documents, other than any U.S. patents and patent publications, is submitted herewith.

The present Information Disclosure Statement is being filed: (1) No later than three months from the application's filing date; (2) Before the mailing date of the first Office Action on the merits (whichever is later); or (3) Before the mailing date of the first Office Action after filing a request for continued examination (RCE) under §1.114, and therefore, no Statement under 37 C.F.R. § 1.97(e) or fee under 37 C.F.R. § 1.17(p) is required.

INFORMATION DISCLOSURE STATEMENT  
U.S. Appln. No.: 10/765,904

The submission of the listed documents is not intended as an admission that any such document constitutes prior art against the claims of the present application. Applicant does not waive any right to take any action that would be appropriate to antedate or otherwise remove any listed document as a competent reference against the claims of the present application.

The USPTO is directed and authorized to charge all required fees, except for the Issue Fee and the Publication Fee, to Deposit Account No. 19-4880. Please also credit any overpayments to said Deposit Account. A duplicate copy of this paper is attached.

Respectfully submitted,



George F. Lehnigk  
Registration No. 36,359

SUGHRUE MION, PLLC  
Telephone: (202) 293-7060  
Facsimile: (202) 293-7860

WASHINGTON OFFICE  
23373  
CUSTOMER NUMBER

Date: August 16, 2004 draft

Substitute for Form 1449 A & B/PTO		Complete if Known	
<b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b>		Application Number	10/765,904
<i>(use as many sheets as necessary)</i>		Confirmation Number	2613
		Filing Date	January 29, 2004
		First Named Inventor	Markus MENGEL
		Art Unit	Not Yet Assigned
		Examiner Name	Not Yet Assigned
Sheet	1	of	1
		Attorney Docket Number	Q79656

U.S. PATENT DOCUMENTS				
Examiner Initials*	Cite No. <sup>1</sup>	Document Number		Name of Patentee or Applicant of Cited Document
		Number	Kind Code <sup>2</sup> (if known)	
		US 6,473,176	B1	10/29/2002 Wang, et al.
		US 6,473,181	B1	10/29/2002 Oakberg
		US 5,886,810		03/23/1999 Siahpooshan, et al.
		US 5,744,721		04/28/1998 Varnum
		US 5,652,673		07/29/1997 Oakberg
		US 6,268,914	B1	07/31/2001 Wang

NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No. <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city, and/or country where published.	Translation <sup>6</sup>
		H. P. POVEL et al, "Two-dimensional polarimeter with a charge-coupled-device image sensor and a piezoelastic modulator," <i>Applied Optics</i> , July 1, 1994, pp. 4254-4259, Vol. 33, No. 19	
		H.P. POVEL et al., "Charge-coupled device image sensor as a demodulator in a 2-D polarimeter with a piezoelastic modulator," <i>Applied Optics</i> , March 10, 1990, pp. 1186-1191, Vol. 29, No. 8	
		D. WRÓBLEWSKI et al., "Polarimetry of motional Stark effect and determination of current profiles DIII-D (invited)," <i>Rev. Sci. Instrum.</i> , October 1992, Vol. 63, No. 10	
		M. TOTZECK et al., "Edge localization of subwavelength structures by use of polarization interferometry and extreme-value criteria," <i>Applied Optics</i> , December 1, 2000, Vol. 39, No. 34	
		M. TOTZECK et al., "High-resolution inspection of 2D-microstructures using multi-mode polarization microscopy," <i>Proceedings of the 2<sup>nd</sup> Conference on Design and Fabrication</i> , 2000, Japan	
		D. CLARKE and J. F. GRAINGER, "Polarized Light and Optical Measurement," Pergamon Press, Oxford, 1971	

Examiner Signature		Date Considered	
--------------------	--	-----------------	--

**\*EXAMINER:** Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

<sup>1</sup>Applicant's unique citation designation number (optional). <sup>2</sup>See Kind Codes of USPTO Patent Documents at [www.uspto.gov](http://www.uspto.gov), MPEP 901.04 or in the comment box of this document. <sup>3</sup> Enter Office that issued the document, by the two-letter code (WIPO Standard ST. 3). <sup>4</sup>For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. <sup>5</sup>Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. <sup>6</sup>Applicant is to indicate here if English language Translation is attached.